

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (currently amended) A head gimbal assembly ~~comprises~~
comprising:

a slider having a read\write sensor;

a suspension to load the slider;

a micro-actuator; wherein

the micro-actuator comprises a piezoelectric unit with two piezoelectric elements and a support base having a base to be coupled with the suspension physically, a moving plate to be coupled with the two piezoelectric elements, and a leading beam to connect with the base and the moving plate.

2. (original) The head gimbal assembly as claimed in claim 1, wherein the base, the moving plate and the leading beam are made from one piece of seamless material.

3. (original) The head gimbal assembly as claimed in claim 2, wherein the seamless material is metal.

4. (original) The head gimbal assembly as claimed in claim 1, wherein the leading beam has a structure to assist a horizontal movement of the moving plate.

5. (original) The head gimbal assembly as claimed in claim 4, wherein the width of the leading beam is narrower than that of the moving plate.

6. (currently amended) The head gimbal assembly as claimed in claim 1, wherein the ~~two piezoelectric elements are two~~ element is a thin film piezoelectric ~~pieces~~ piece or ceramic piezoelectric ~~pieces~~ piece.

7. (currently amended) The head gimbal assembly as claimed in claim 1, wherein a plurality of electrical pads ~~[[is]]~~ are formed on each of the two piezoelectric elements.

8. (original) The head gimbal assembly as claimed in claim 7, wherein the two piezoelectric elements have three electrical pads consisting of two voltage applied pads and a ground pad shared by the two piezoelectric elements.

9. (currently amended) The head gimbal assembly as claimed in claim 7, wherein the suspension comprises a ~~flexure~~ flexure having a suspension ~~tongue, the suspension~~ tongue which has a plurality of electrical pads disposed on a predetermined position thereof corresponding to the electrical pads on the two piezoelectric elements.

10. (currently amended) The head gimbal assembly as claimed in claim 9, wherein the base of the micro-actuator electrically couples with the electrical pads and physically couples with the ~~flexure~~ flexure by anisotropic conductive film.

11. (currently amended) The head gimbal assembly as claimed in claim 1, wherein the moving plate of the support base physically and electrically ~~couple~~ couples with the slider by anisotropic conductive film or adhesive bonding.

12. (currently amended) A micro-actuator ~~comprises~~ comprising:

a piezoelectric unit with two piezoelectric elements; and

a support base; wherein the support base has a base, a moving plate to be coupled with the two piezoelectric elements, and a leading beam to connect with the base and the moving plate.

13. (original) The micro-actuator as claimed in claim 12, wherein the base, the moving plate and the leading beam are made from one piece of seamless material.

14. (original) The micro-actuator as claimed in claim 13, wherein the seamless material is metal.

15. (original) The micro-actuator as claimed in claim 12, wherein the two piezoelectric elements are two thin film piezoelectric pieces or ceramic piezoelectric pieces.

16. (currently amended) The micro-actuator as claimed in claim 12, wherein a plurality of electrical pads ~~[[is]]~~ are formed on each of the two piezoelectric elements.

17. (original) The micro-actuator as claimed in claim 16, wherein the two piezoelectric elements have three electrical pads consisting of two voltage applied pads and a ground pad shared by the two piezoelectric elements.

18. (currently amended) A method of forming a micro-actuator ~~comprises~~ comprising the steps of:

(1) forming a piezoelectric unit having two piezoelectric elements;

(2) forming a support base having a base, a moving plate, and a leading beam to connect with the base and the moving plate; and

(3) bonding the piezoelectric unit to one side of the support base.

19. (currently amended) The method ~~of forming a micro-actuator~~ as claimed in claim 18, wherein step (2) comprises the following steps: (a) forming a set of the support bases; and (b) dividing the set of the support bases into a single support base.

20. (currently amended) The method ~~of forming a micro-actuator~~ as claimed in claim 18, wherein step (a) is performed by die ~~punishing~~ punching a raw sheet to a set of the support bases.

21. (currently amended) The method ~~of forming a micro-actuator~~ as claimed in claim 18, wherein step (a) is performed by: forming a multi-layer sheet consisted of raw sheet and spacer sheet alternately; and ~~then~~ cutting the multi-layer sheet to a set of the support bases.

22. (currently amended) The method of forming a micro-actuator as claimed in claim 18, wherein step (a) is performed by molding a bulk of support base bars ~~consisted of~~ having a set of the support bases.

23. (currently amended) A method of forming a head gimbal assembly ~~comprises~~ comprising the steps of:

(A) forming a slider, a suspension and a micro-actuator, wherein forming the micro-actuator comprises: forming the piezoelectric unit having two piezoelectric elements; forming a support base having a base, a moving plate, and a leading beam to connect with the base and the moving ~~plate~~, plate; and bonding the piezoelectric unit to one side of the support base;

(B) coupling the micro-actuator physically and electrically with the slider by anisotropic conductive film or adhesive bonding; and

(C) electrically bonding the slider to the suspension by gold ball bonding or solder bump bonding.